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PATENT APPLICATION

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kiyoshi ARAKAWA

Application No.: 10/622,143

Filed: July 18, 2003

For: EXPOSURE APPARATUS, MAINTENANCE
METHOD THEREFOR, SEMICONDUCTOR
DEVICE MANUFACTURING METHOD
USING THE APPARATUS, AND
SEMICONDUCTOR MANUFACTURING
FACTORY

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Examiner: Hung Nguyen
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Group Art Unit: 2851
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Confirmation No.: 1879
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Allowed: November 23, 2004
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March 14, 2005
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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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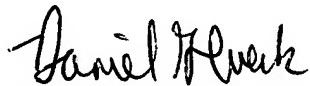
Sir:

For the convenience of the public, Applicant requests that the following documents be placed in the Official File: (1) February 14, 2005 European Search Report of a foreign counterpart application corresponding to the above-referenced application; (2) U.S. Patent No. 4,766,309 (Kudo); and (3) JP-A 6-275489 with English-language Abstract from Patent Abstracts of Japan, Vol. 18, No. 684 (E-1650).

The Search Report cites items (2) and (3), as well as EP 1 030 351, which is of record.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our below-listed address.

Respectfully submitted,



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